

Zinc(II) and Cadmium(II) Complexes, $[M(^iPr_2P(X)NC(Y)NC_5H_{10-\kappa^2-X,Y})_2]$ (X and Y= O, S), as Single Source Precursors for Metal Sulfide Thin films

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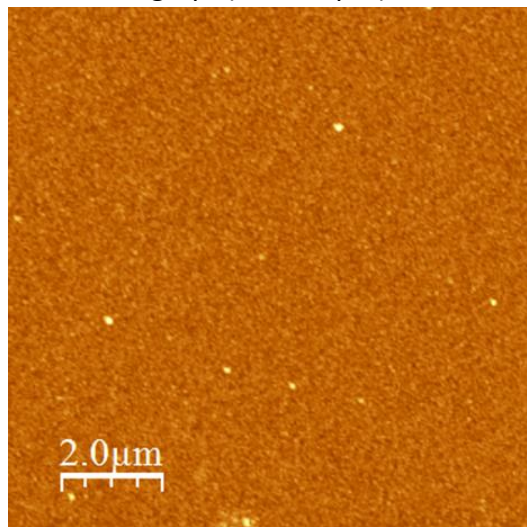
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1. Table S1. Crystallographic Data for compounds **2**, **6**, **7** and **9**

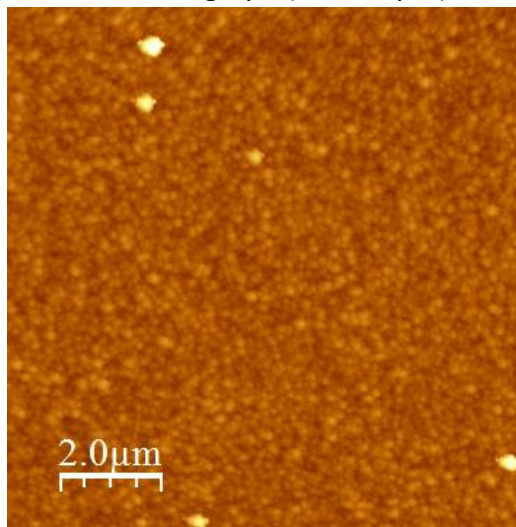
Compound	2	6	7	9
Formula	C ₁₂ H ₂₅ N ₂ O ₂ PS	C ₂₄ H ₄₈ N ₄ O ₂ P ₂ S ₂ Zn	C ₂₄ H ₄₈ CdN ₄ P ₂ S ₄	C ₂₄ H ₄₈ CdN ₄ O ₂ P ₂ S ₂
M [g/mol]	276.37	616.09	695.24	663.12
Crystal size (mm)	0.463 x 0.312 x 0.246	0.407 x 0.307 x 0.174	0.516 x 0.316 x 0.144	0.299 x 0.250 x 0.112
Crystal system	Monoclinic	Monoclinic	Triclinic	Monoclinic
Space group	C 2/c (15)	P2 ₁ /n (14)	P-1 (2)	P2 ₁ /n (14)
ρ_{calc} (g cm ⁻³)	1.129	1.296	1.390	1.372
Z	8	4	2	4
a (Å)	10.0025(6)	11.9623(2)	9.9720(2)	11.9249(2)
b (Å)	18.7416(11)	11.1902(2)	13.3201(2)	11.0983(2)
c (Å)	17.4507(10)	23.5940(3)	13.5216(2)	24.2600(5)
α (°)	90.00	90.00	86.0570(10)	90.00
β (°)	96.041(2)	91.5400(10)	68.82 (10)	90.3960(10)
γ (°)	90.00	90.00	82.7220(10)	90.00
V (Å ³)	3253.2(3)	3157.16(9)	1660.72(5)	3210.64(10)
μ (mm ⁻¹)	0.287	1.038	1.025	0.936
F(000)	1200	1312	724	1384
Reflections Collected	19321	27833	19444	15124
Unique reflections	2981; 0.0395	5765, 0.0399	6095, 0.0281	5884; 0.0365
R_{int}				
R1, wR2 [$I > 2\sigma(I)$]	0.0467; 0.1274	0.0296; 0.0751	0.0288, 0.0757	0.0299; 0.0597
R1, wR2 (all data)	0.0559; 0.1346	0.0389; 0.0787	0.0352, 0.0799	0.0482; 0.0670
Correction Method	None	Analytical	Analytical	Analytical
Goof	1.054	1.036	1.052	0.949

2. Figure S1. Micrographs of as-deposited and annealed ZnS thin films: 4F, 5F and 6F (unannealed) and 4Fa, 5Fa and 6Fa (annealed).

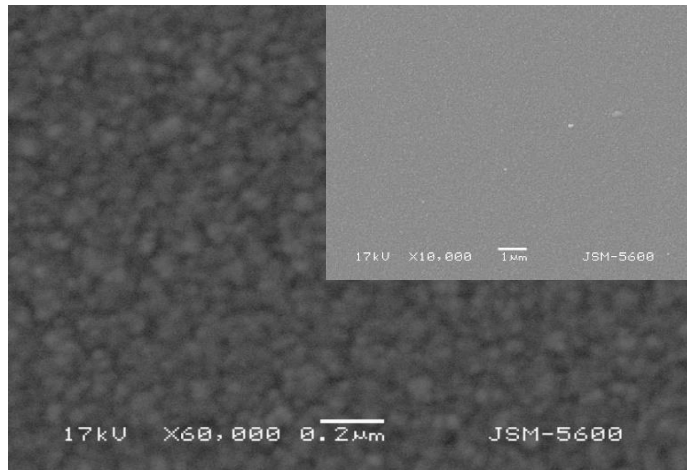
AFM micrograph(10 x 10 μm): **4F**



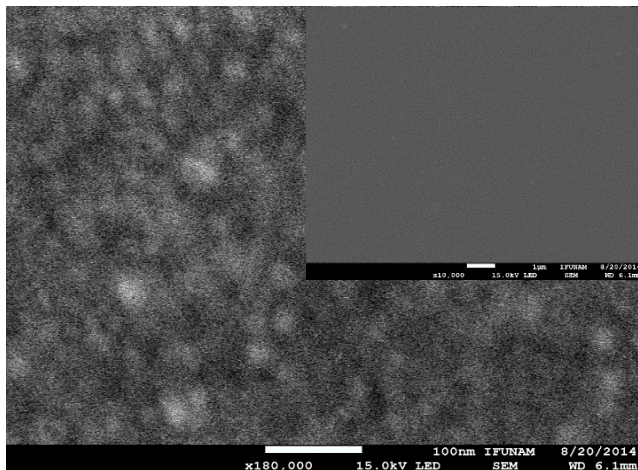
AFM micrograph (10 x 10 μm): **4Fa**



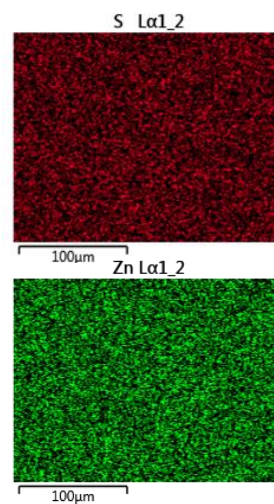
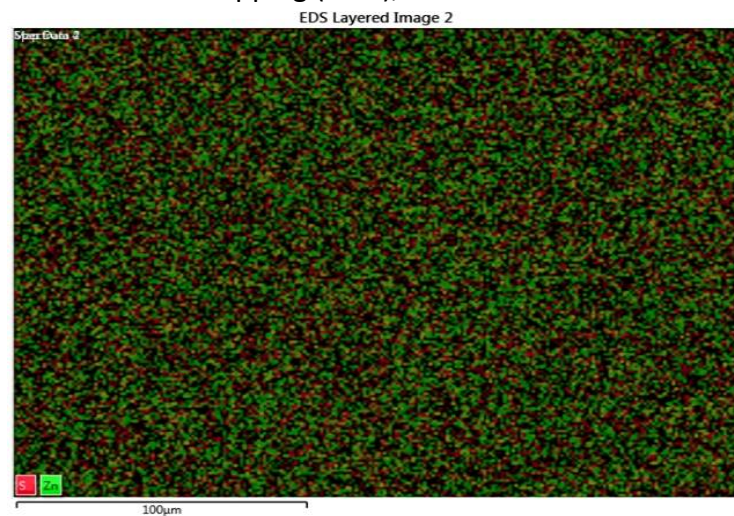
Low (inset) and high magn. SEM images: **4Fa**



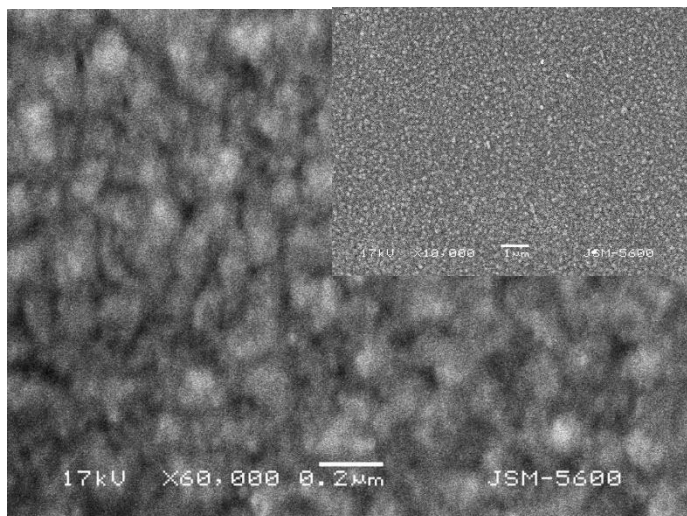
and **5F**



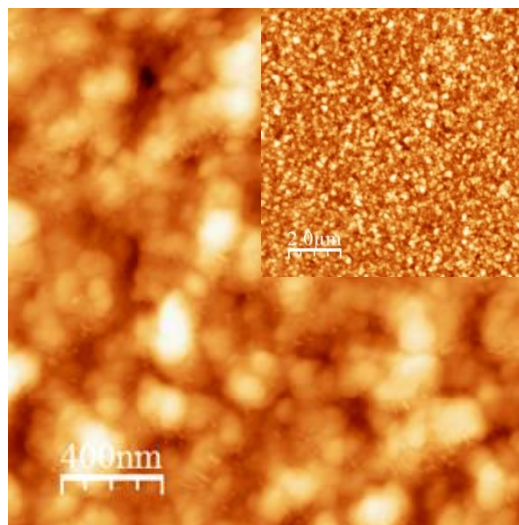
5F: Elemental Mapping (SEM), sulfur and zinc distribution.



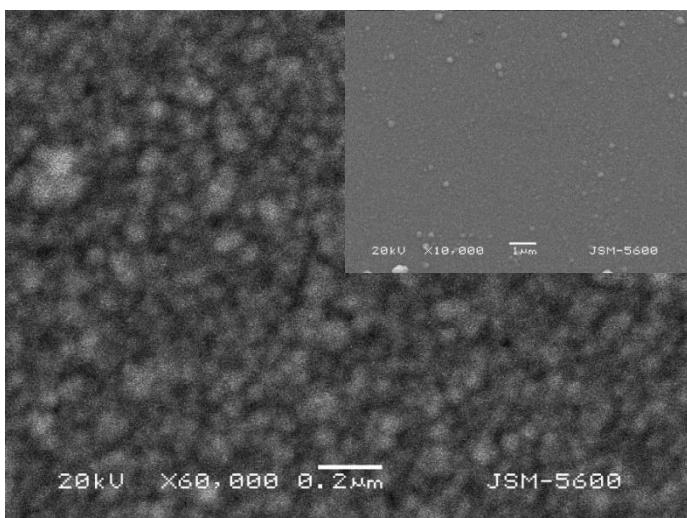
Low (inset) and high magn. SEM images: **5Fa**



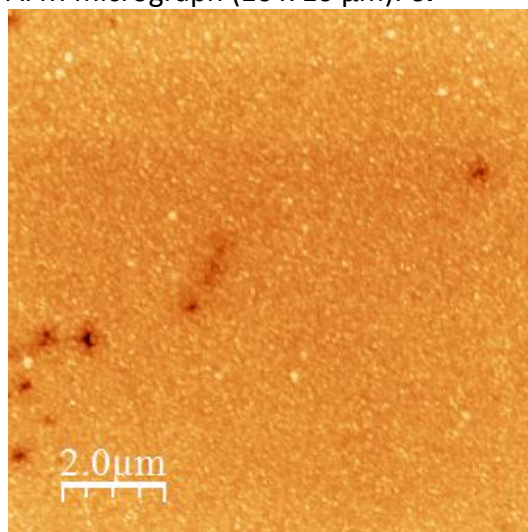
AFM (1 x 1 μm, inset 10 x 10 μm): **5Fa**



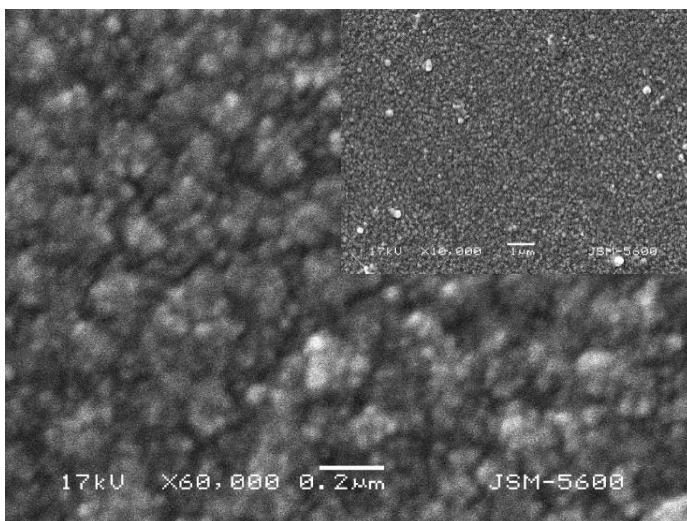
Low (inset) and high magnification SEM images: **6F**



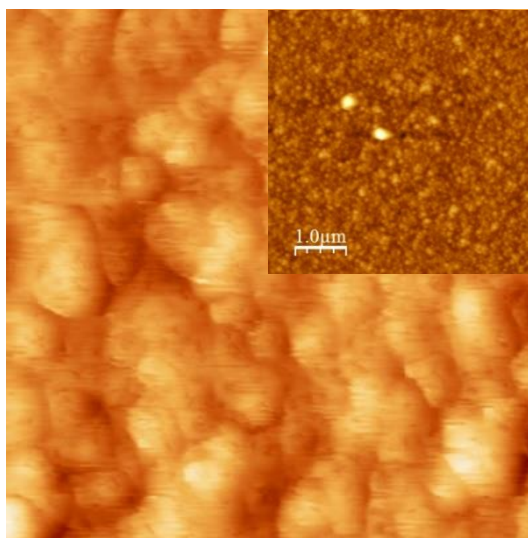
AFM micrograph (10 x 10 μm): **6F**



Low (inset) and high magnification SEM images: **6Fa**

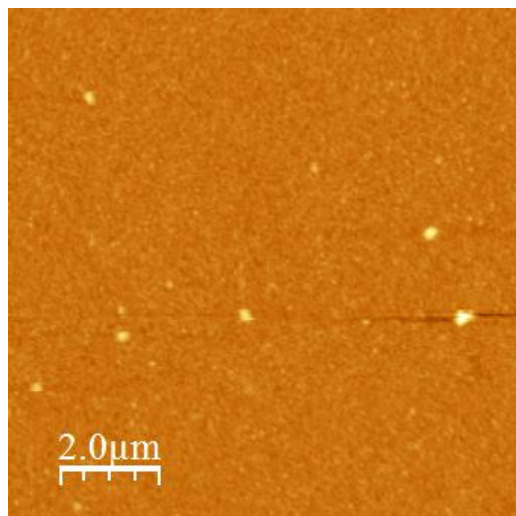


AFM micrograph (1 x 1 μm, inset 10 x 10 μm): **6Fa**

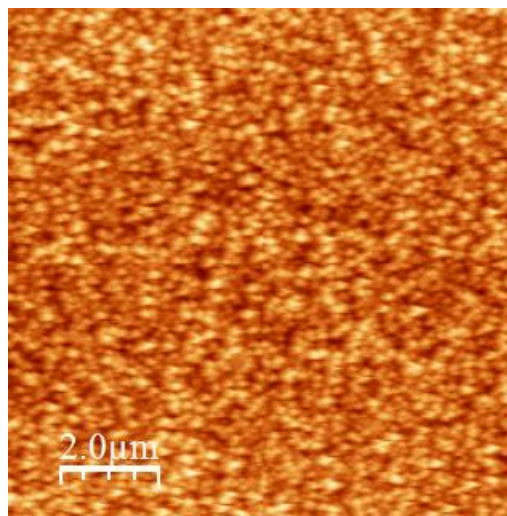


3. Figure S2. Micrographs of as-deposited and annealed CdS thin films: 7F, 8F and 9F (unannealed) and 7Fa, 8Fa and 9Fa (annealed) and AFM micrographs of annealed 8Fa and 9Fa.

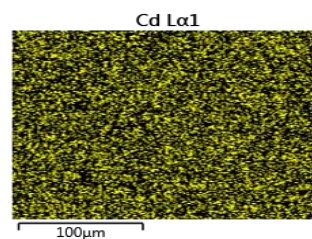
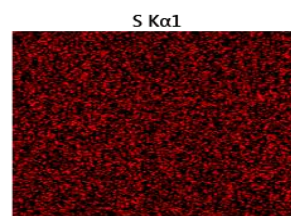
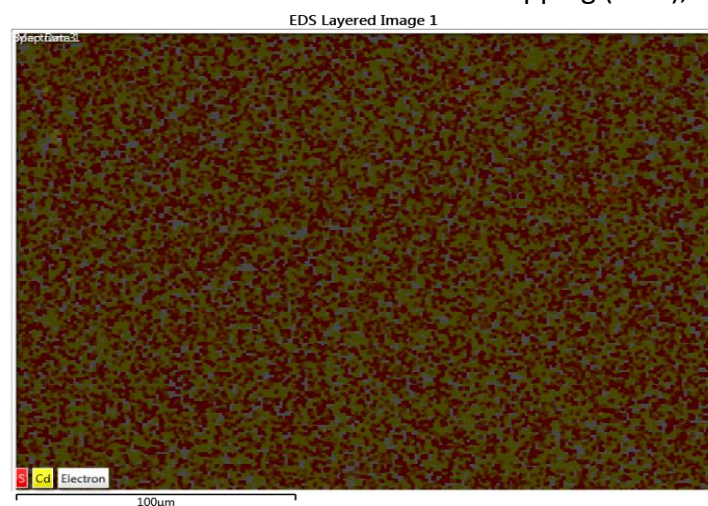
FM micrograph(10 x 10 μm): 7F



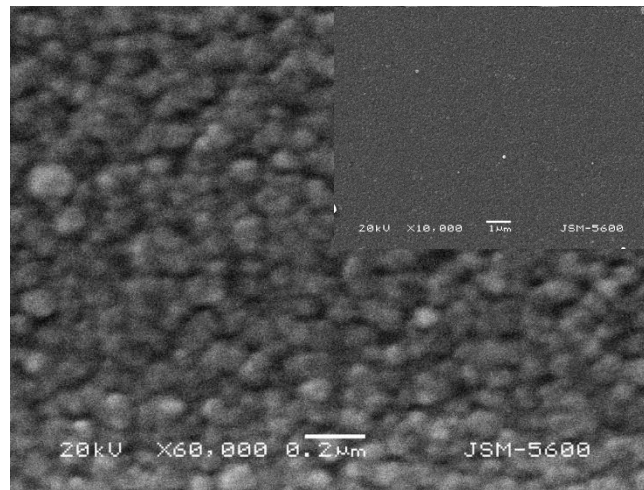
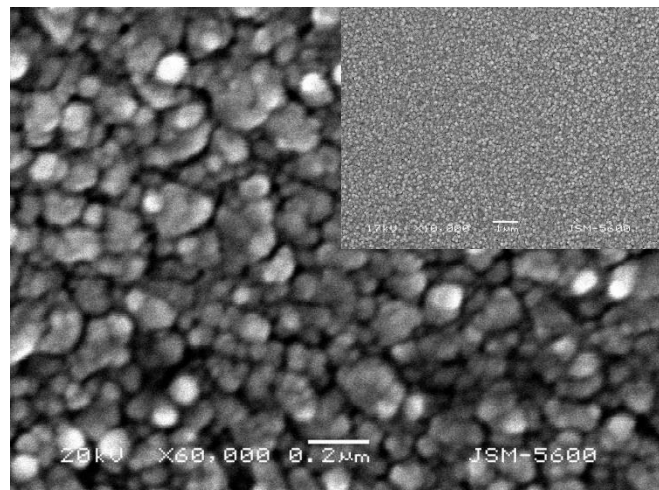
AFM micrograph (10 x 10 μm):7Fa



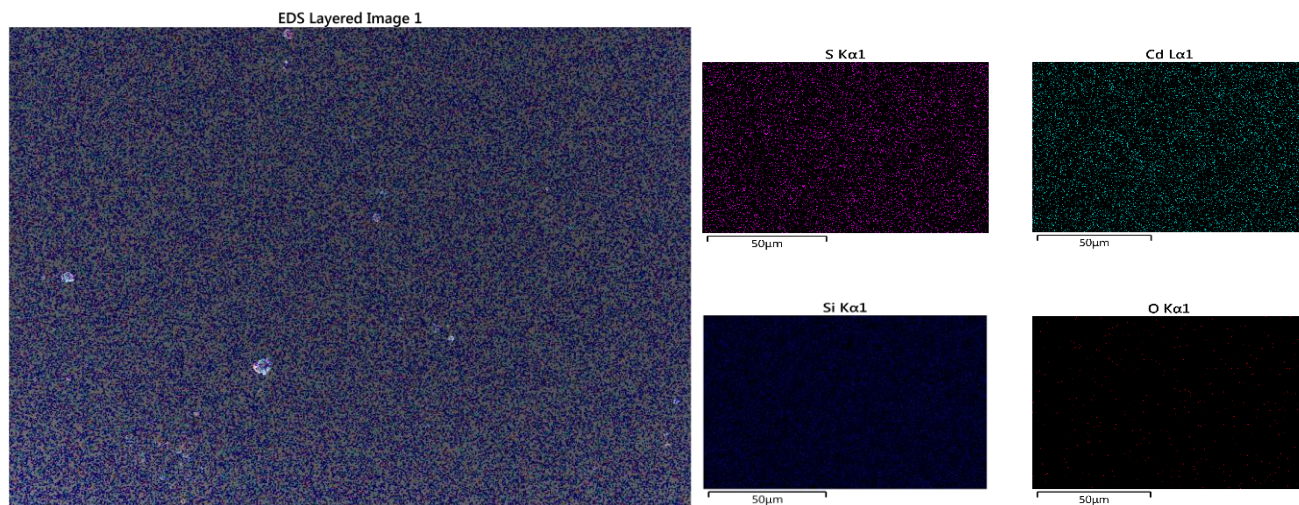
7F: Elemental Mapping (SEM), sulfur and zinc distribution



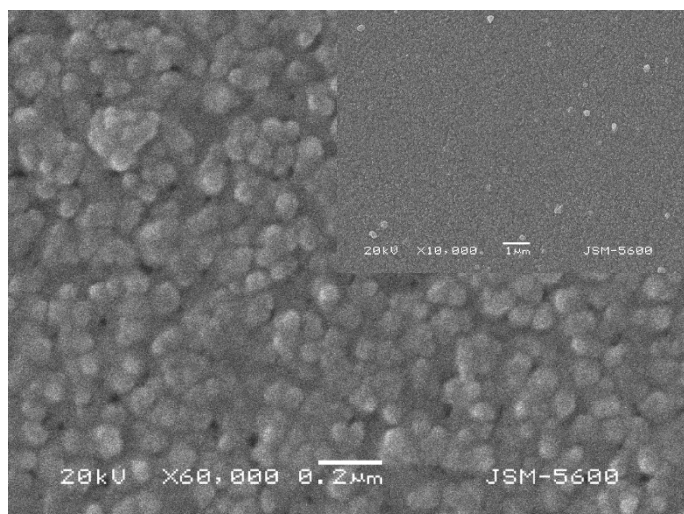
Low (inset) and high magnification SEM images: 7Fa and 8F



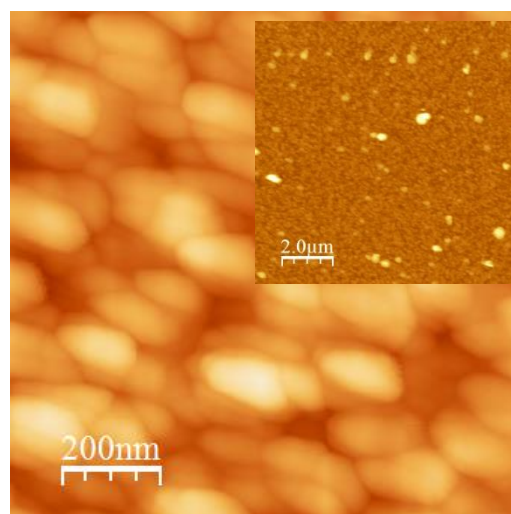
8F Elemental Mapping (SEM), sulfur, cadmium and substrate: silicium and oxygen.



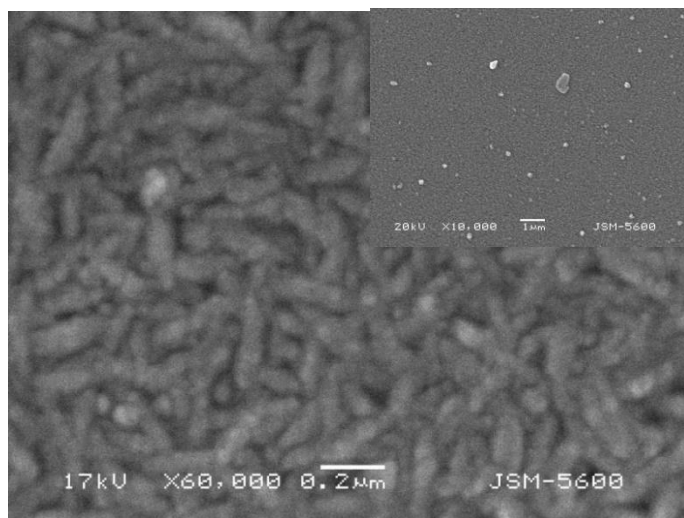
Low (inset) and high magnification SEM images: 8Fa



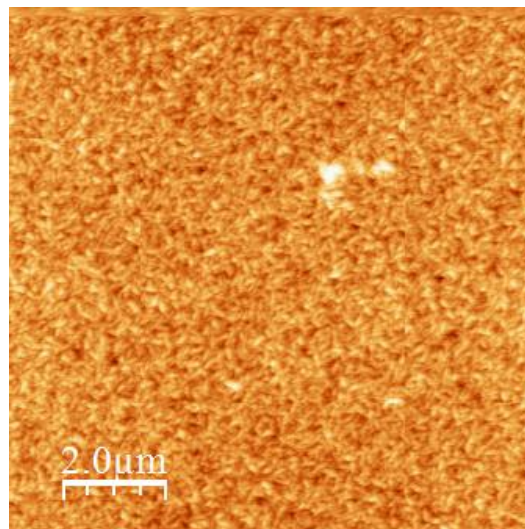
AFM micrograph (1 x 1 μm, inset 10 x 10 μm): 8Fa



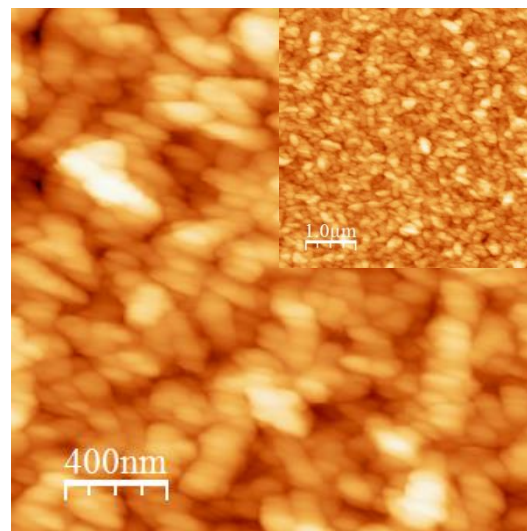
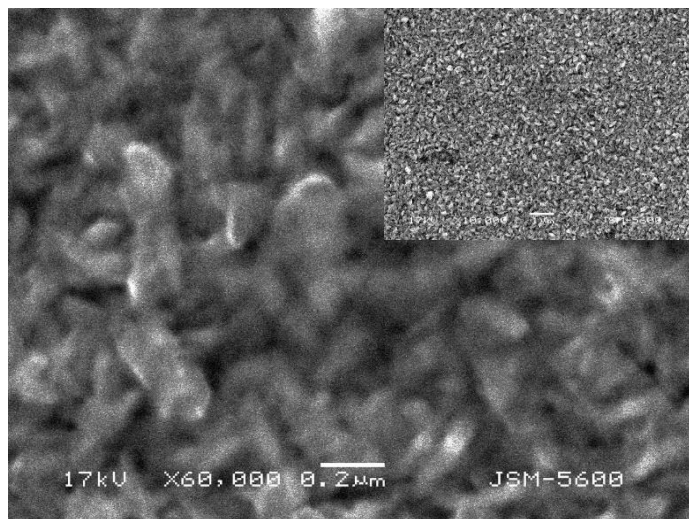
Low (inset) and high magnification SEM images: 9F



AFM micrograph (10 x 10 μm): 9F



Low (inset) and high magnification SEM images: **9Fa** AFM micrograph (2 × 2 μm, inset 5 × 5 μm): **9Fa**



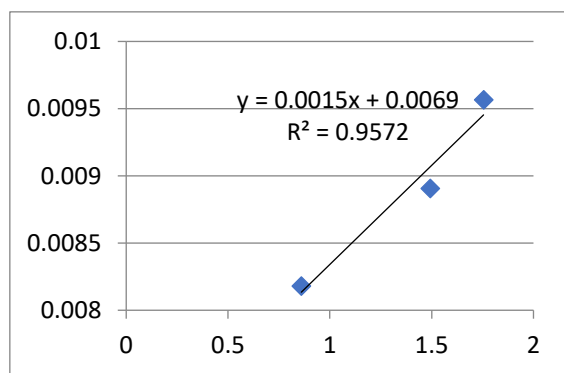
4. X-ray diffraction structural analysis. The average crystallite size was calculated from Debye–Scherrer equation (1) 2 for all unannealed thin films produced at 450°C (**4F-9F**) and the corresponding annealed films at 600°C (**4F-a-9F-a**).

$$D = \frac{0.94\lambda}{\beta \cos \theta} \quad (1)$$

where λ is the wavelength of the X-ray used; β is the width of the peak at half the maximum intensity in radians and θ is the Bragg diffraction angle. The strain (ϵ) and grain size of the samples were calculated by the Williamson–Hall (W–H) relation,¹ according to the following equation (2)

$$\beta \cos \theta = \frac{K\lambda}{D} + 4\epsilon \sin \theta \quad (2)$$

The strain is estimated from the slope of the plots of $\beta \cos \theta / \lambda$ versus $\sin \theta / \lambda$, while the crystallite size (D) from the intercept on the Y-axis



X	Y
4sinθ	βcosθ
0.85996405	0.00818168
1.49259886	0.00890596
1.75473943	0.00956739

Figure S3. Williamson–Hall plot for **9F**

5. The optical band gap (E_g) were estimated using Tauc's relationship:²

$$\alpha h\nu = B(h\nu - E_g)^{1/m} \quad (4)$$

where α is the absorption coefficient, $h\nu$ is the incident photon energy, B is the energy-dependent constant, E_g is the optical band gap of the material, and m is the transition coefficient which can be 1/2, 3/2, 2, and 3, in this case $m = 1/2$ for direct allowed transitions and α was evaluated using the following relation

$$\alpha = -\frac{1}{t} \ln T \quad (5)$$

$$E_{\text{phonon}} = \frac{hc}{\lambda} \quad (6)$$

where t is the film thickness, T the transmittance. The optical energy gap, E_g of the investigated MS thin films, were obtained from plot $(\alpha h\nu)^2$ versus the photon energy ($h\nu$) by extrapolating linear part to intersect ($h\nu$) axis at $(\alpha h\nu)^2 = 0$ (Figure S4 for annealed films).

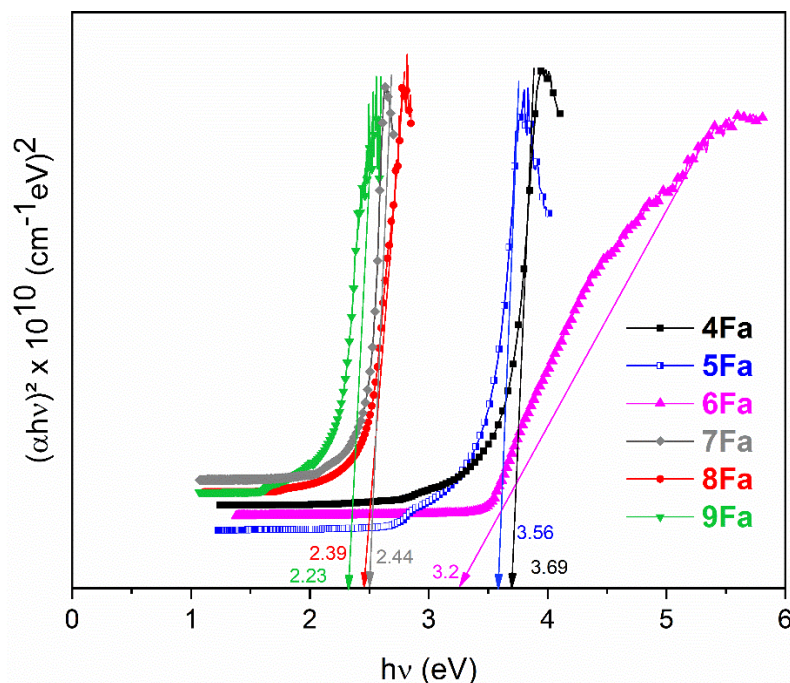


Figure S4. $(\alpha h\nu)^2$ vs $h\nu$ plot showing the estimated optical band gap of annealed films (600 °C) 4Fa–9Fa.

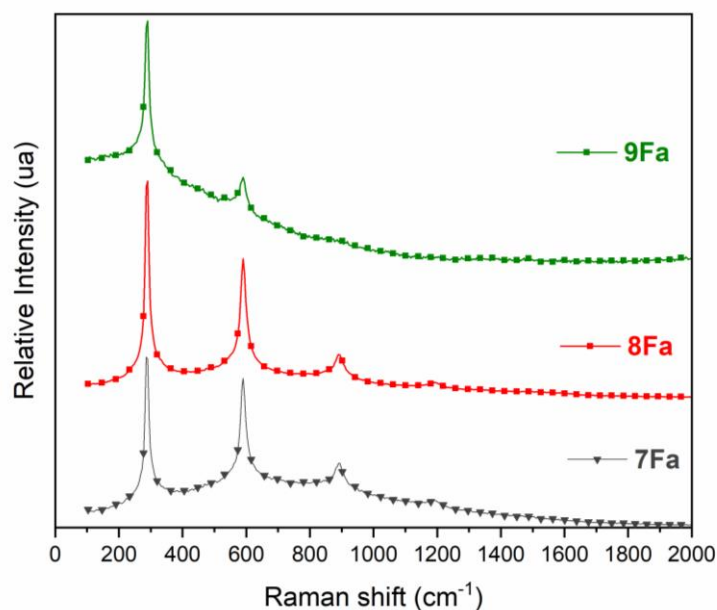
6. **Table 2.** Band gap (E_g) of our films and reported MS thin films obtained from different SSPs and techniques.

M	Precursor	Preparation method (solvent)	T_{prep} (°C)	E_g (eV)	Ref
Zn	4	AACVD (Toluene)	450	3.9	*
Zn	4		annealed (600)	3.69	*
Zn	5		450	3.64	*
Zn	5		annealed (600)	3.56	*
Zn	6		450	3.43	*

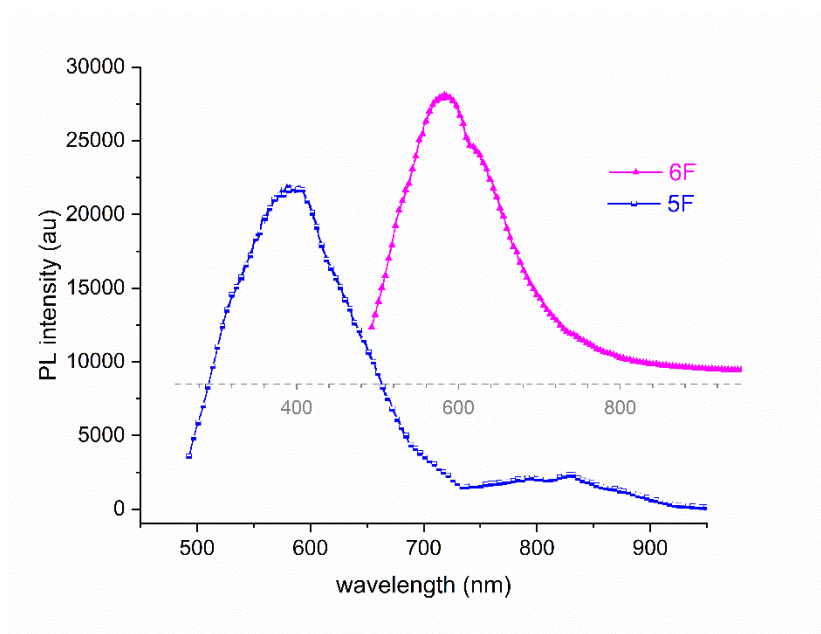
Zn	6		annealed (600)	3.2	*
Zn	$\text{Zn}(\text{N}(\text{SCNMe}_2)_2)_2$	AACVD (THF)	300-450	3.23, 3.36	³
Zn	$\text{Zn}(\text{N}(\text{SCNEt}_2)_2)_2$		300-450	2.62 -3.21	³
Zn	$\text{Zn}(\text{NSO}(\text{CN}^i\text{Pr}_2)_2)_2$		300-450	3.23 -3.31	³
Zn	$\text{Zn}(^i\text{Pr}_2\text{P}(\text{S})\text{NHP}(\text{S})^i\text{Pr}_2\text{P})_2$	LP-MOCVD	450	3.64	⁴
Zn	$[\text{Zn}(\text{SOCPh})_2\text{lutidine}_2\cdot\text{H}_2\text{O}]$	One-step thermal decomposition	600	3.58	⁵
Zn	$\text{Zn}(\text{C}_{10}\text{H}_{11}\text{N}_3\text{S})_2$	AACVD (methanol)	400-500	3.70	⁶
Zn	$\text{Zn}(\text{C}_8\text{H}_8\text{ClN}_3\text{S})_2$		400-500	3.91	⁶
Zn	$[\text{Zn}\{^i\text{PrNC}(\text{S})\text{NMe}_2\}_2]_2$	AACVD (THF)	200-350	3.71-3.79	⁷
Cd	7	AACVD (Toluene)	450	2.5	*
Cd	7		annealed (600)	2.44	*
Cd	8		450	2.44	*
Cd	8		annealed (600)	2.39	*
Cd	9		450	2.28	*
Cd	9		annealed (600)	2.23	*
Cd	$\text{Cd}(\text{N}(\text{SCNMe}_2)_2)_2$	AACVD (THF)	350-500	2.41-2.43	³
Cd	$\text{Cd}(\text{N}(\text{SCNEt}_2)_2)_2$		350-500	2.32-2.41	³
Cd	$\text{Cd}(\text{NSO}(\text{CN}^i\text{Pr}_2)_2)_2$		350-500	2.34-2.41	³
Cd	$\text{Cd}(^i\text{Pr}_2\text{P}(\text{S})\text{NHP}(\text{S})^i\text{Pr}_2\text{P})_2$	LP-MOCVD	450	2.30	⁴
Cd	$\text{Cd}[\text{S}_2\text{CNCy}_2]_2\cdot\text{py}$	AACVD (pyridine)	350-450	2.4	⁸
Cd	$\text{Cd}[\text{S}_2\text{CNC}_5\text{H}_{10}]_2\cdot\text{py}$	AACVD (chloroform)	350-450	2.4	⁹
Cd	$\text{Cd}[\text{S}_2\text{CN}(\text{C}_6\text{H}_{13})_2]_2\cdot$	AACVD (THF)	400/450	2.43/2.41	¹⁰
Cd	$\text{Cd}[\text{S}_2\text{CNEt}_2]_2\cdot$		400/450	2.41/2.42	¹⁰
Cd	$\text{Cd}[\text{S}_2\text{C}(\text{NC}_5\text{H}_{10})]_2$		400/450	2.37/2.40	¹⁰
Cd	$\text{Cd}[\text{EtOCS}_2]_2$		400/450	2.44/2.49	¹⁰
Cd	$\text{Cd}[\text{EtOCS}_2]_2 \text{ R-py}_2$	AACVD (THF)	220 and 350	2.25-2.40	¹¹
Cd	$\text{Cd}(\text{EtOCS}_2)_2\text{py}_2$	Thermolysis/annealed	150/350	2.4	¹²

*This work

7. Figure S5. Raman spectra of annealed CdS films (**7Fa** - **9Fa**) under 488 nm excitation.



8. **Figure S6.** PL spectra ($\lambda_{\text{exc}} = 488 \text{ nm}$) of as-deposited ZnS films: **5F** and **6F** (450°C).



Notes and references

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